

AMENDMENTS TO THE CLAIMS

1. (Original) A system, comprising:
 - a loading fixture to load and support a suspension when a micro-actuator coupled to a slider is attached;
 - an adhesive controller to apply and cure an adhesive substance to the suspension;
 - a pitch static attitude and roll static attitude (PSA/RSA) monitor to take a first measurement of the pitch static attitude and roll static attitude of the micro-actuator on the suspension;
 - a gap monitor to take a second measurement of a gap between the micro-actuator and the suspension; and
 - a rotatable positioning tool to hold the micro-actuator and the slider in a position relative to the suspension for attachment and to adjust the position of the micro-actuator and the slider in response to the first and second measurements.
2. (Original) The system of claim 1, wherein the rotatable positioning tool is a vacuum nozzle system with a stepped nozzle opening shaped to the micro-actuator and the slider.
3. (Original) The system of claim 1, wherein the rotatable positioning tool adjusts a level of the micro-actuator and the slider.
4. (Original) The system of claim 1, wherein the gap monitor is a camera system.

5. (Original) The system of claim 1, wherein a base plate of the suspension is used as a reference point for said measurements.
6. (Original) The system of claim 1, wherein the micro-actuator is coupled to the suspension by the adhesive substance and said measurements are made prior to curing the adhesive substance.
7. (Original) The system of claim 1, wherein the position of the micro-actuator is adjusted in response to said measurements prior to curing the adhesive substance.
8. (Original) A method, comprising:
 - supporting a suspension while a micro-actuator with a slider is attached;
 - holding the micro-actuator in a position relative to the suspension for attachment;
 - applying an adhesive substance on a predetermined position of the suspension for tacking the micro-actuator on the suspension;
 - taking a first measurement of the pitch static attitude and roll static attitude of the micro-actuator on the suspension;
 - taking a second measurement of a gap between the micro-actuator and the suspension;
 - adjusting the position of the micro-actuator in response to the first and second measurements; and
 - curing the adhesive substance after adjusting the position of the micro-actuator.

9. (Original) The method of claim 8, wherein the first measurement is taken with a laser measurement system.
10. (Original) The method of claim 8, wherein the second measurement is taken by a camera system.
11. (Original) The method of claim 8, further comprising using a base plate of the head suspension as a reference point for measurements.
12. (Original) A positioning device, comprising:
a pitch static attitude and roll static attitude (PSA/RSA) monitor to take a first measurement of a pitch static attitude and roll static attitude of a micro-actuator on a suspension;
a gap monitor to take a second measurement of a gap between the micro-actuator and the suspension; and
a rotatable positioning tool to hold the micro-actuator in a position relative to the suspension for attachment and to adjust the position of the micro-actuator in response to said measurements.
13. (Original) The positioning device of claim 12, wherein the rotatable positioning tool is a vacuum nozzle system with a stepped nozzle opening to better grasp the micro-actuator.

14. (Original) The positioning device of claim 12, wherein the rotatable positioning tool is adjustable thirty degrees left and right along an axis normal to the head suspension.
15. (Original) The positioning device of claim 12, wherein the PSA/RSA monitor is a laser measurement system.
16. (Original) The positioning device of claim 12, wherein the gap monitor is a camera system.
17. (Original) The positioning device of claim 12, wherein a base plate of the suspension is used as a reference point for measurements.
18. (Original) The positioning device of claim 12, wherein the micro-actuator is coupled to the suspension by an epoxy and at least one of the first and second measurements are taken prior to curing the epoxy.
19. (Original) The positioning device of claim 12, wherein the position of the micro-actuator is adjusted in response to at least one of the first and second measurements prior to curing the epoxy.